



US00D839224S

(12) **United States Design Patent**  
**Yamaki et al.**

(10) **Patent No.:** **US D839,224 S**  
(45) **Date of Patent:** **\*\* Jan. 29, 2019**

(54) **ELASTIC MEMBRANE FOR SEMICONDUCTOR WAFER POLISHING**

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(\*\*) Term: **15 Years**

(21) Appl. No.: **29/606,998**

(22) Filed: **Jun. 9, 2017**

(30) **Foreign Application Priority Data**

Dec. 12, 2016 (JP) ..... 2016-026913  
Dec. 12, 2016 (JP) ..... 2016-026914  
Dec. 12, 2016 (JP) ..... 2016-026915

(51) **LOC (11) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D13/182**

(58) **Field of Classification Search**  
USPC ..... D13/182; 451/66, 288, 289  
CPC ..... B24B 37/30; B24B 41/061; B24B 49/16  
See application file for complete search history.

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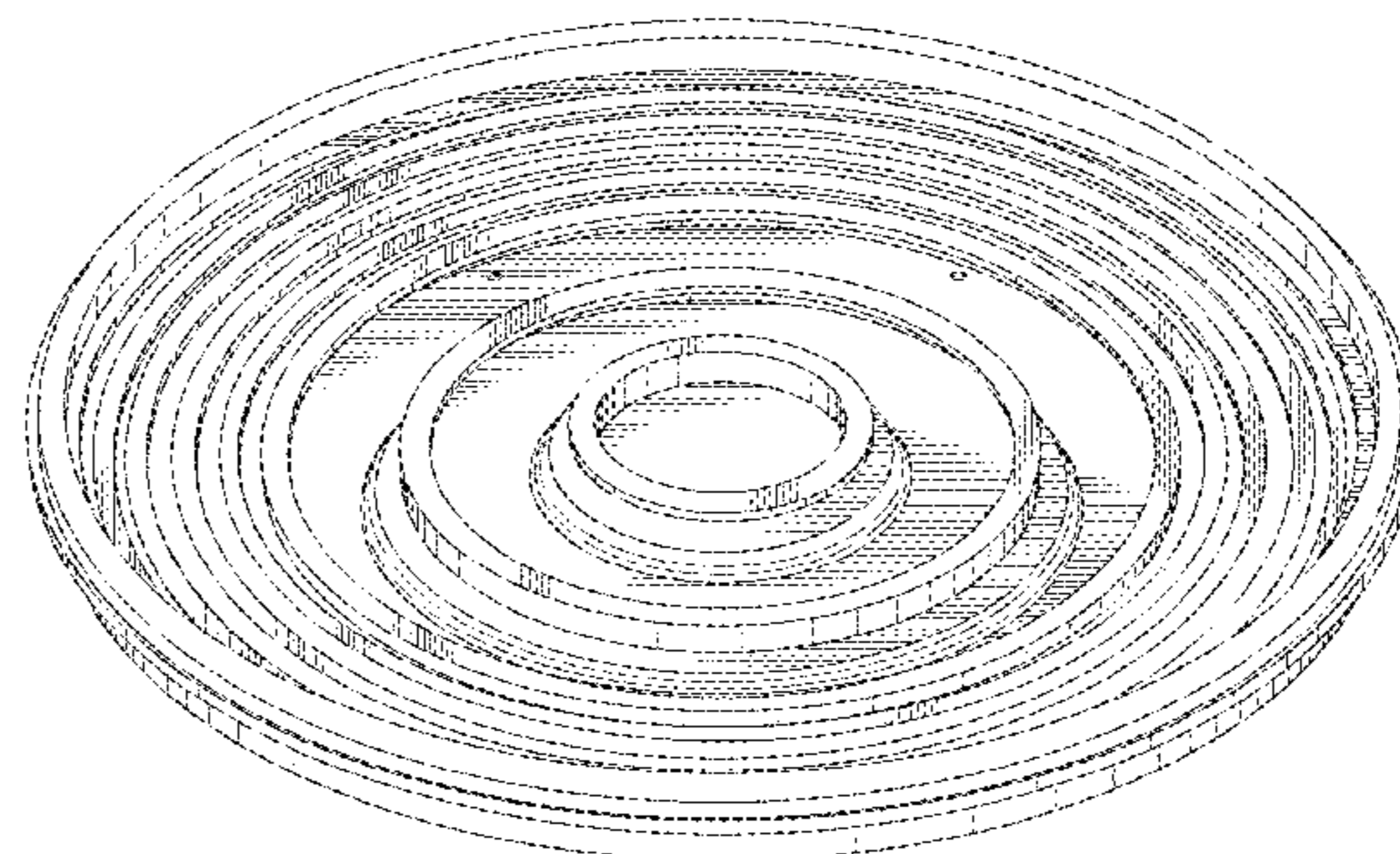
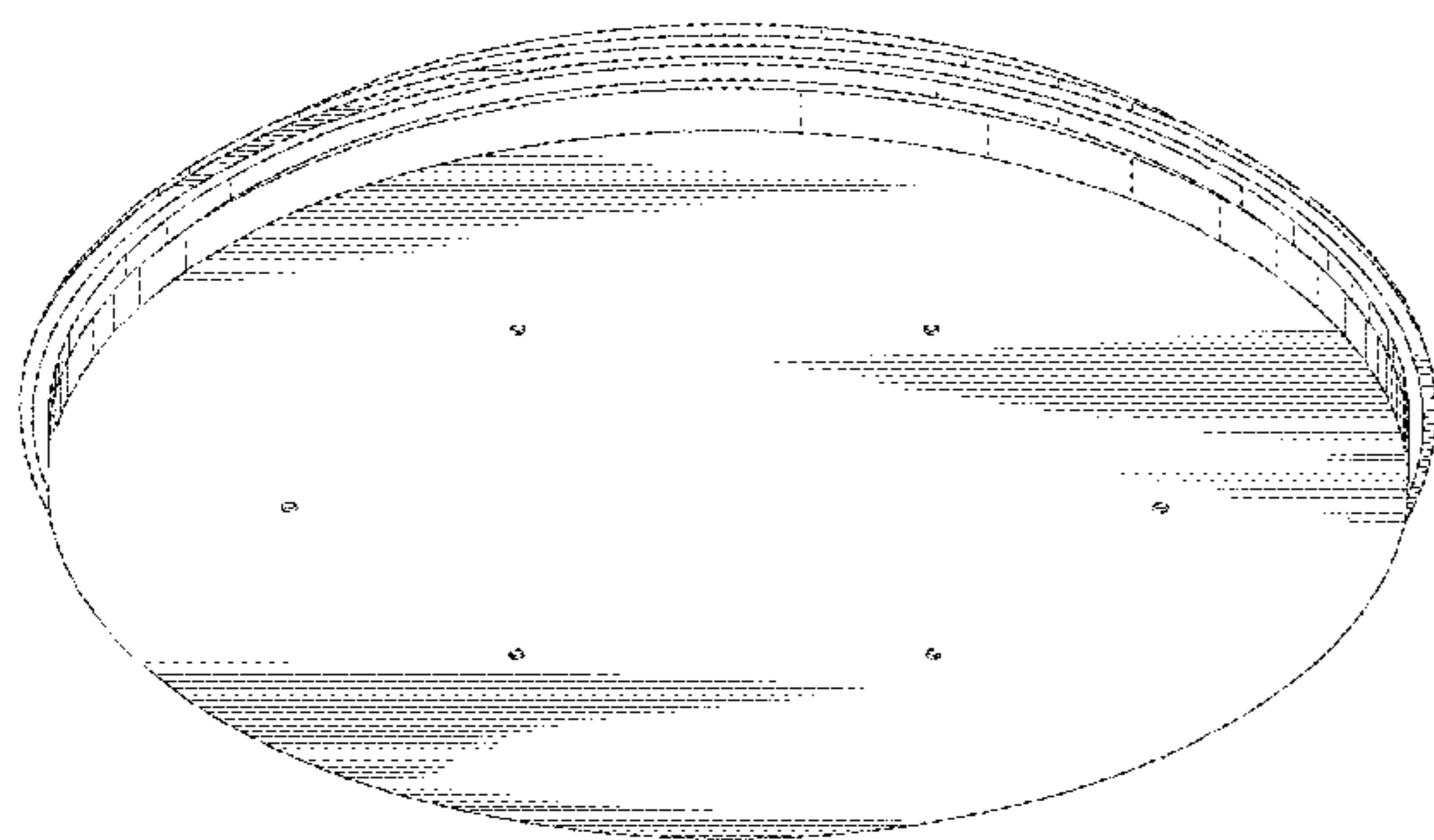
(57) **CLAIM**

The ornamental design for an elastic membrane for semiconductor wafer polishing, as shown and described.

**DESCRIPTION**

FIG. 1 is a bottom perspective view of an elastic membrane for semiconductor wafer polishing showing our new design; FIG. 2 is a top perspective view thereof; FIG. 3 is a bottom view thereof; FIG. 4 is a top view thereof; FIG. 5 is a front view thereof, a rear view being identical thereto; FIG. 6 is a right-side view thereof, a left-side view being identical thereto; FIG. 7 is a cross-sectional view taken along line 7-7 of FIG. 4; and, FIG. 8 is an enlarged portion view labeled FIG. 8 in FIG. 7. The dash-dot lines in FIG. 7 represent the boundary line of the enlarged portion view shown in FIG. 8.

**1 Claim, 6 Drawing Sheets**



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FIG. 1

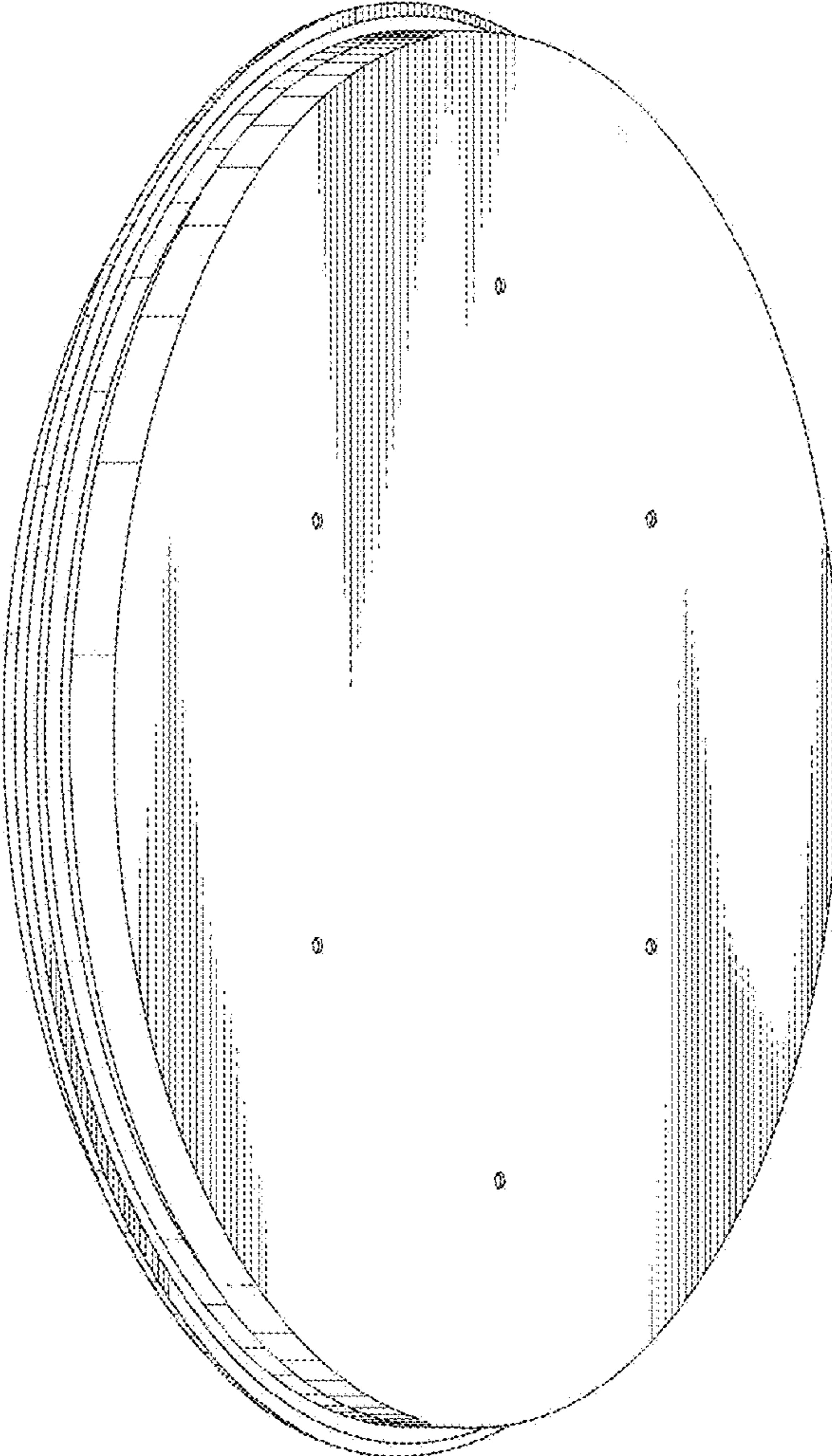


FIG. 2

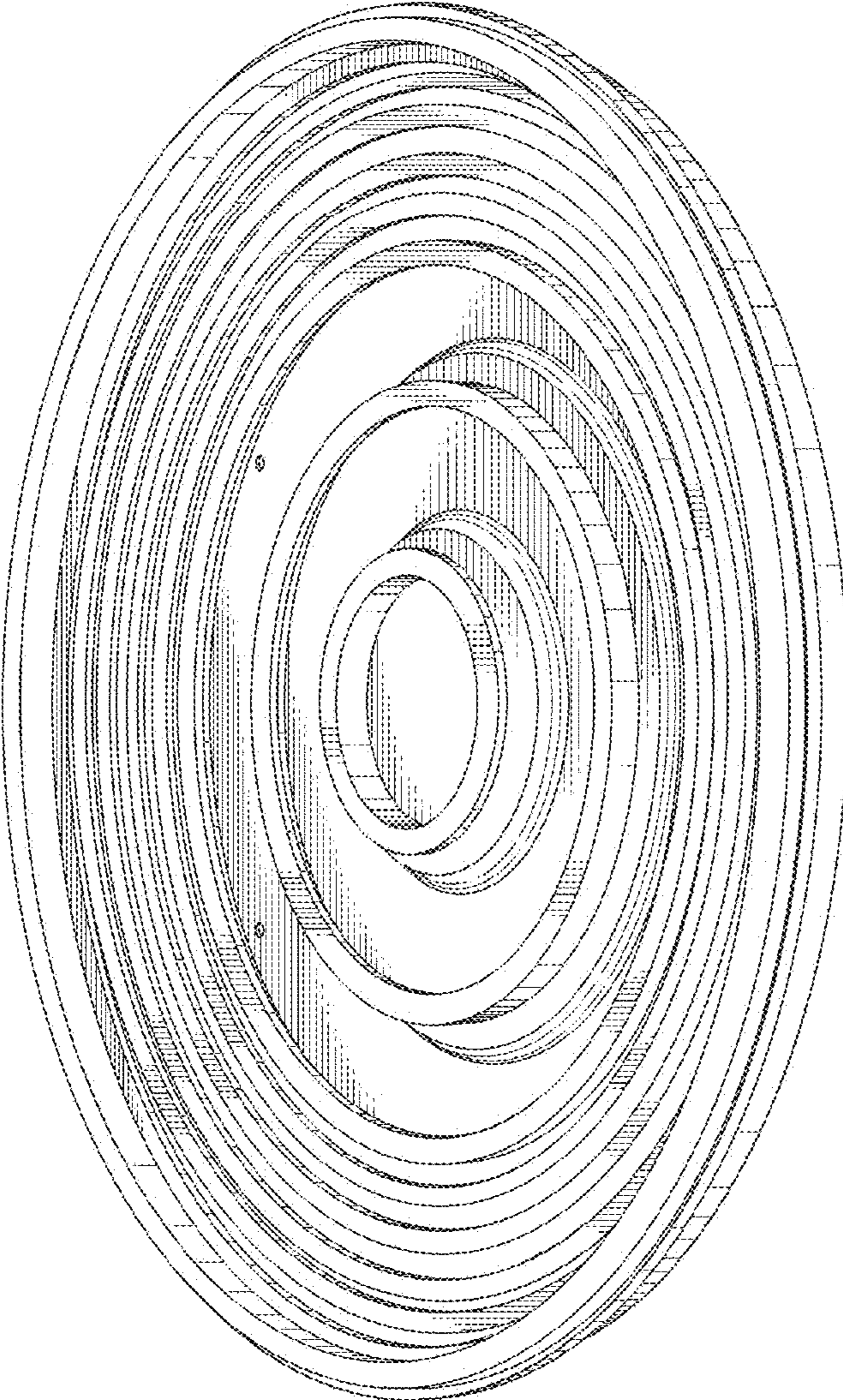


FIG. 3

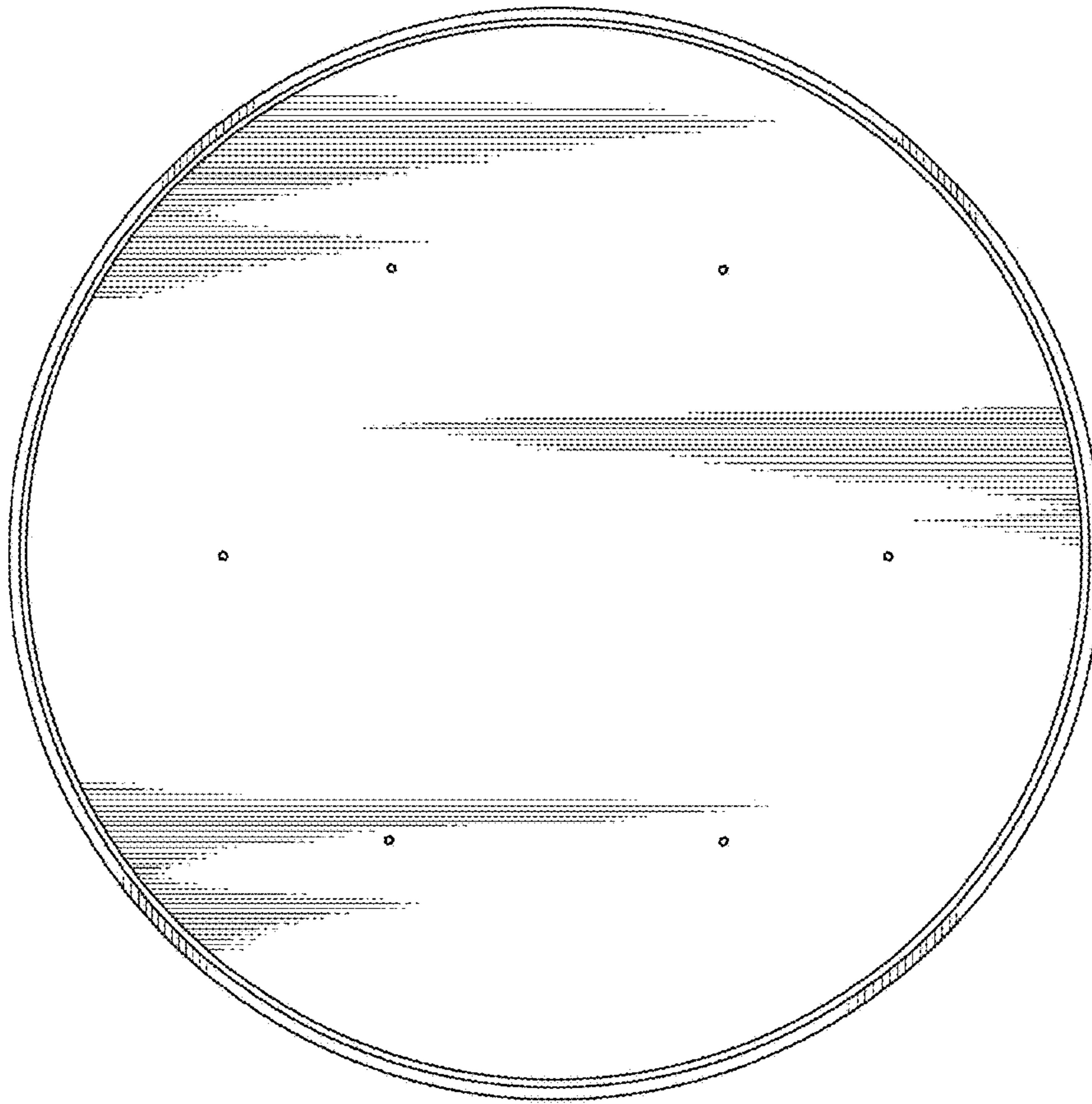


FIG. 4

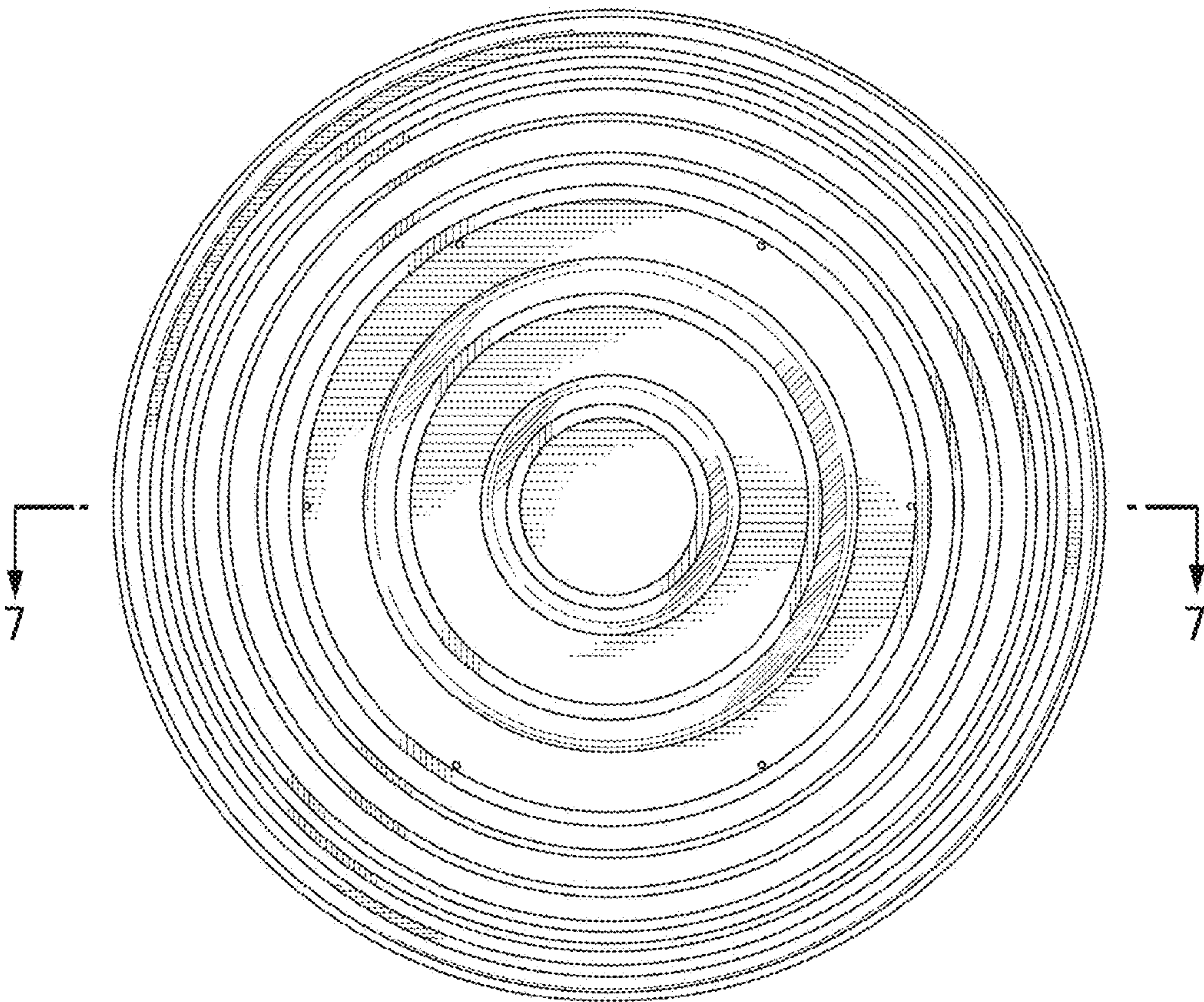


FIG. 5



FIG. 6



FIG. 7

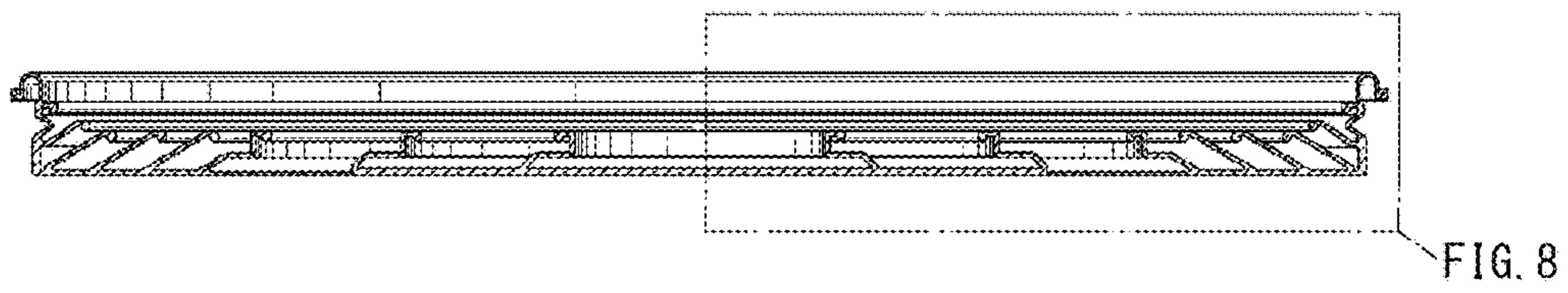


FIG. 8

